



SEMIPROBE®

Test • Inspect • Innovate

SUCCESSFUL APPLICATION: MEMS - 1021



Specific Requirements:

A customer needed a semi-automatic probe system, which would be used for production testing of 150 mm and 200 mm MEMS wafers using probe cards. The system required a dispense system and compatibility with Keithley S500 test system.

SemiProbe Solution:

- PS4L SA-8 Semi-automatic 200 mm probe system:
 - 200 mm programmable X, Y, Z and theta stage with control electronics
 - 200 wafer chuck
 - PILOT Software Suite – Navigator, Wafer Map and Autoalign
 - Vibration isolation table
- Probe card holder with coarse and fine theta adjustment
- Microscope post with linear and coaxial X and Y microscope movement
- Stereo zoom microscope with 100 mm working distance
- CCTV color camera system with 24” monitor
- Custom dispense system – pump with two dispense units
- Test instrumentation – Keithley S500 Series controlled from Automated Characterization Suite software via SemiProbe GPIB driver